

Accepted Manuscript

Analytical study of electromechanical buckling of a micro spherical elastic film on a compliant substrate Part II: Postbuckling analysis

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PII: S0020-7683(17)30019-7
DOI: [10.1016/j.ijsolstr.2017.01.020](https://doi.org/10.1016/j.ijsolstr.2017.01.020)
Reference: SAS 9436



To appear in: *International Journal of Solids and Structures*

Received date: 20 January 2016
Revised date: 1 January 2017
Accepted date: 10 January 2017

Please cite this article as: Samy Abu-Salih , Analytical study of electromechanical buckling of a micro spherical elastic film on a compliant substrate Part II: Postbuckling analysis, *International Journal of Solids and Structures* (2017), doi: [10.1016/j.ijsolstr.2017.01.020](https://doi.org/10.1016/j.ijsolstr.2017.01.020)

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Highlights

- The electromechanical postbuckling analysis of a spherical elastic film is presented.
- The preferred buckling pattern can be controlled by determining geometrical parameters.
- The effect of nonlinear stiffness of the elastic compliant substrate is studied.
- The total potential energy method is used for analyzing the electromechanical postbuckling analysis.

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